

Notice of References Cited	Application/Control No. 10/784,566	Applicant(s)/Patent Under Reexamination JIN ET AL.	
	Examiner Jermele M. Hollington	Art Unit 2829	Page 1 of 1

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NON-PATENT DOCUMENTS

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	U	Bengtsson et al, Interface charge control of directly bonded silicon structures, 08/01/1989, Journal of Applied Physics, Volume 66, 1231-1239			
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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